IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Hiroshi ONO et al.

Serial Number: Not yet assigned

(§371 of international application No. PCT/JP2003/07554)

Filed: December 12, 2005

For: POLISHING SLURRY FOR METAL, AND POLISHING METHOD

Attorney Docket Number: 053460

38834

Customer Number:

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450 December 12, 2005

Sir:

In compliance with 37 C.F.R. §1.56, Applicants direct the attention of the Patent and Trademark Office to the documents listed on the attached PTO/SB/08. A copy of each non-U.S. document is enclosed herewith.

If there are any fees due in connection with the filing of this paper, please charge Deposit Account No. 50-2866.

Respectfully submitted,

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SGA/yap

Enclosure: PTO/SB/08, 10 documents and international search report.

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Combined Form PTO/SB/08A&B

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

of

Complete if Known				
Application Number	New application			
Confirmation Number				
Filing Date	December 12, 2005			
First Named Inventor	Hiroshi ONO et al.			
Art Unit				
Examiner Name				
Attorney Docket Number	053460			

U.S. PATENT DOCUMENTS						
Examiner Cite Initials* No.1	Cita	Document Number		Publication Date		
			Name of Patentee or Applicant of Cited Document			
	1	US 4,944,836		07-31-1990	Kaus D. Beyer et al.	
		US				
		US				
		US				
		US				

FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date	Name of Patentee or	m 1 4 6
		Country Code ³	Number⁴	Kind Code ⁵ (if known)	MM-DD-YYYY	Applicant of Cited Document	Translation ⁶
	2	JP	2002-134442		05-10-2002	Hitachi Chem. Co., Ltd.	Abstract, cited in the ISR
	3	EPO	0 696 651 A1		02-14-1996	MEC Co., Ltd.	Yes, cited in the ISR
	4	ЕРО	1 260 607 A2		11-27-2002	Shipley Co., LLC	In English, cited in the ISR
	5	JP	11-172467		06-29-1999	Ebara Densan Ltd.	Abstract, cited in the ISR
	6	DE	199 26 117 A1		12-16-1999	Ebara Densan Ltd.	No, cited in the ISR
	7	JP	11-204942		07-30-1999	Hitachi Chem. Co., Ltd.	Abstract, cited in the ISR
	8	PCT	WO 00/13217		03-09-2000	Hitachi Chem. Co., Ltd.	Abstract, cited in the ISR
	9	JP	02-278822	·	11-15-1990	Int'l. Business Mach. (IBM)	Abstract, cited in the spec.
	10	JP	8-83780		03-26-1996	Toshiba Corp.	Abstract, cited in the spec.
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Examiner Initials*	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city, and/or country where published.	Translation ⁶	
	11	F. B. KAUFMAN et al.; "Chemical-Mechanical Polishing for Fabricating Patterned W Metal Features as Chip Interconnects;" Journal of the Electrochem. Society, Vol. 138, No. 11, November 1991, pp.3460-3465. Cited in the specification.		

				1
Examiner Signature			Date Considered	

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